IN THE CLAIMS

- 1-29. (currently cancelled)
- 30-39. (previously cancelled)
- 40-43. (currently cancelled)
- 44-45. (previously cancelled)
- 46-52. (currently cancelled)
- 53. (New) A process for the preparation of a plurality of well-defined structures, said process comprises the following steps, not necessarily in the order as listed:
 - (a) providing a support web;
 - (b) coating a layer of a radiation curable material on said support web;
 - (c) providing a photomask as a continuous loop which comprises a pattern corresponding in form to at least one of said well-defined structures;
 - (d) aligning said photomask loop with said support web so that at least a portion of said photomask loop is in generally parallel orientation to at least a portion of said support web;
 - selectively exposing at least a portion of said radiation curable material to radiation through said photomask, leaving at least a portion of said radiation curable material unexposed;
 - (f) moving said photomask loop and said support web in a synchronized motion so that at least a portion of said photomask loop and at least a portion of said support web are moving in parallel in substantially the same direction; and
 - (g) removing said unexposed radiation curable material to form a plurality of said well-defined structures.
- 54. (New) The process of Claim 53 wherein said photomask loop and said support web are moving at substantially the same speed.
- 55. (New) A process for the preparation of a plurality of microcups, which process comprises, not necessarily in the order listed:
 - (a) providing a support web which comprises a plurality of conductor lines for addressing said microcups;
 - (b) coating a layer of a radiation curable material on said support web;



- (c) providing a photomask as a continuous loop which comprises a pattern corresponding in form to at least one of said microcups;
- (d) selectively exposing at least a portion of said radiation curable material to radiation through said photomask loop, leaving at least a portion of said radiation curable material unexposed; and
- (e) removing said unexposed radiation curable material so as to form said microcups.
- 56. (New) The process of Claim 55 further comprising filling said microcups with an electrophoretic display pigment/solvent composition or liquid crystal display composition and sealing said filled microcups.
- 57. (New) The process of Claim 56 wherein said step of filling comprises filling substantially all of said microcups with a single electrophoretic display pigment/solvent composition or liquid crystal <u>display</u> composition to form a monochrome display.
- 58. (New) The process of Claim 56 wherein said step of filling comprises filling said microcups with different electrophoretic display pigment/solvent compositions or liquid crystal <u>display</u> compositions to form a multi-color display.
- 59. (New) A process for the preparation of a plurality of well-defined structures, said process comprises the following steps, not necessarily in the order as listed:
 - (a) providing a support web which comprises a plurality of elements;
 - (b) coating a layer of a radiation curable material on said support web;
 - (c) providing a photomask as a continuous loop which comprises a pattern having areas of transparency and areas of opacity;
 - (d) aligning at least a portion of said photomask loop and at least a portion of said support web in a manner that said areas of opacity correspond to said elements on said support web;
 - selectively exposing at least a portion of said radiation curable material through said areas of transparency of said photomask loop, leaving at least a portion of said radiation curable material unexposed;
 - (f) moving said photomask loop and said support web in a synchronized motion so as to maintain a predetermined spatial relationship between at least a portion of said photomask loop and at least a portion of said support web

9

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- wherein said synchronized motion comprises moving at least a portion of said photomask loop and at least a portion of said support web in parallel in substantially the same direction; and
- (g) removing said unexposed radiation curable material to form a plurality of said well-defined structures.
- 60. (New) The process of Claim 59 wherein said photomask loop and said support web are moving at substantially the same speed.
- 61. (New) The process of Claim 60 wherein said photomask loop and said support web are moving at a constant speed.
- 62. (New) The process of Claim 59 wherein steps (e) and (f) are carried out simultaneously.
 - 63. (New) The process of Claim 59 wherein step (b) is carried out continuously.
 - 64. (New) The process of Claim 59 wherein step (e) is carried out continuously.
 - 65. (New) The process of Claim 59 wherein step (f) is carried out continuously.
 - 66. (New) The process of Claim 59 further comprising the following steps:
 - (i) detecting one of said elements or a pre-formed marker on said support web;
 - (ii) detecting one of said areas of opacity or a pre-formed marker on said photomask loop; and
 - (iii) controlling the motion of said support web and said photomask loop in response to steps (i) and (ii) so as to bring at least a portion of said support web into said predetermined spatial relationship with at least a portion of said photomask loop.
- 67. (New) A process for the preparation of microcups which process comprises, not necessarily in the order listed:
 - (a) providing a support web which comprises a plurality of conductor lines for addressing said microcups;
 - (b) coating a layer of a radiation curable material on said support web;
 - (c) providing a photomask as a continuous loop which comprises a pattern having areas of transparency and areas of opacity and said areas of transparency correspond in form to wall structure of said microcups;



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- (d) aligning at least a portion of said photomask loop and at least a portion of said support web in a manner that said areas of opacity correspond to said conductor lines on said support web;
- (e) selectively exposing at least a portion of said radiation curable material through said areas of transparency of said photomask loop, leaving at least a portion of said radiation curable material corresponding to areas of opacity of said photomask loop unexposed; and
- (f) moving said photomask loop and said support web in a synchronized motion so as to maintain a predetermined spatial relationship between at least a portion of said photomask loop and at least a portion of said support web.
- 68. (New) The process of Claim 67 further comprising removing said unexposed radiation curable material to form said microcups.
- 69. (New) The process of Claim 68 which step of removing said unexposed radiation curable material is carried out continuously.
- 70. (New) The process of Claim 55 wherein said conductor lines are transparent to visible light.
- 71. (New) The process of Claim 67 wherein said conductor lines are transparent to visible light.
- 72. (New) A process for the preparation of a multi-color display, which process comprises:
 - (a) providing a support web which comprises a plurality of pre-formed microcups with top openings;
 - (b) laminating a layer of a radiation curable material over said top openings of said microcups;
 - (c) providing a photomask as a continuous loop which comprises a pattern corresponding in form to said top openings of a first pre-selected subset of microcups;
 - (d) selectively exposing said radiation curable material to radiation through said photomask loop; and
 - (e) removing said exposed radiation curable material so as to re-open said first pre-selected subset of microcups.

- 73. (New) The process of Claim 72 wherein said radiation curable material is a positively working photoresist.
- 74 (New) The process of Claim 72 further comprising the steps of filling said re-opened first pre-selected subset of microcups with a first electrophoretic display pigment/solvent composition or liquid crystal display composition and sealing said filled first pre-selected subset of microcups.
 - 75. (New) The process of Claim 74 further comprising the following steps:
 - (i) providing a photomask as a continuous loop which comprises a pattern corresponding in form to said top openings of a second pre-selected subset of microcups;
 - (ii) selectively exposing said radiation curable material to radiation through said photomask loop; and
 - (iii) removing said exposed radiation curable material so as to re-open said second pre-selected subset of microcups.
- 76. (New) The process of Claim 75 further comprising the steps of filling said re-opened second pre-selected subset of microcups with a second electrophoretic display pigment/solvent composition or liquid crystal display composition and sealing said filled second pre-selected subset of microcups.
 - 77. (New) The process of Claim 76 further comprising the following steps:
 - (i) providing a photomask as a continuous loop which comprises a pattern corresponding in form to said top openings of a third pre-selected subset of microcups;
 - (ii) selectively exposing said radiation curable material to radiation through said photomask loop; and
 - (iii) removing said exposed radiation curable material so as to re-open said third pre-selected subset of microcups.
- 78. (New) The process of Claim 77 further comprising the steps of filling said re-opened third pre-selected subset of microcups with a third electrophoretic display pigment/solvent composition or liquid crystal display composition and sealing the filled third pre-selected subset of microcups.

- (New) The process of Claim 78 further comprising laminating said sealed 79. first, second and third subsets of microcups with a top laminate.
- (New) A process for the preparation of a multi-color display, which process 80. comprises:
 - providing a support web which comprises a plurality of pre-formed microcups (a) with top openings;
 - laminating a layer of a positively working photoresist over said top openings (b) of said microcups;
 - providing a photomask as a continuous loop which comprises a pattern (c) having areas of transparent and areas of opacity and said areas of transparency correspond in form to said top openings of a first pre-selected subset of microcups;
 - selectively exposing said positively working photoresist to radiation through (d) said areas of transparency of said photomask loop; and
 - removing said exposed positively working photoresist so as to re-open said (e) first pre-selected subset of microcups.
- (New) The process of Claim 80 further comprising the steps of filling said 81. re-opened first pre-selected subset of microcups with a first electrophoretic display pigment/solvent composition or liquid crystal display composition and sealing said filled first pre-selected subset of microcups.
 - (New) The process of Claim 81 further comprising the following steps: 82.
 - providing a photomask as a continuous loop which comprises a pattern (i) having areas of transparency and areas of opacity and said areas of transparency correspond in form to said top openings of a second preselected subset of microcups;
 - selectively exposing said positively working photoresist to radiation through (ii) said areas of transparency of said photomask loop; and
 - removing said exposed positively working photoresist so as to re-open said (iii) second pre-selected subset of microcups.
- (New) The process of Claim 82 further comprising the steps of filling said 83. re-opened second pre-selected subset of microcups with a second electrophoretic display

pigment/solvent composition or liquid crystal display composition and sealing said filled second pre-selected subset of microcups.

- (New) The process of Claim 83 further comprising the following steps: 84.
- providing a photomask as a continuous loop which comprises a pattern (i) having areas of transparency and areas of opacity and said areas of transparency correspond in form to said top openings of a third pre-selected subset of microcups;
- selectively exposing said positively working photoresist to radiation through · (ii) said areas of transparency of said photomask loop; and
 - removing said exposed positively working photoresist so as to re-open said (iii) third pre-selected subset of microcups.
- (New) The process of Claim 84 further comprising the steps of filling said 85. re-opened third pre-selected subset of microcups with a third electrophoretic display pigment/solvent composition or liquid crystal display composition and sealing said filled third pre-selected subset of microcups.
- (New) The process of Claim 85 further comprising laminating over said 86. sealed first, second and third subsets of microcups with a top laminate for addressing said microcups.
- (New) The process of Claim 86 wherein said top laminate is coated with an 87. adhesive.
- (New) A photolithographic process comprising imagewise exposure through 88. a moving photomask synchronized with a moving web substrate wherein said web substrate comprises indium-tin oxide (ITO) on PET (polyethylene terephthalate), PEN (polyethylene naphthalate) or polycarbonate and said ITO is coated with a radiation curable material.
- (New) The process of Claim 88 wherein said radiation curable material is a 89. positively working photoresist.
- (New) The process of Claim 89 wherein said web substrate is ITO/PET 90. coated with a positively working photoresist.
- (New) The process of Claim 90 wherein the positively working photoresist is 91. developed after exposure and the ITO/PET is etched to expose discrete patterns.

92. (New) The process of Claim 91 wherein said positively working photoresist is stripped.